

- ▶ **100 μm XYZ Piezo Scanner for TT-2 AFM**
Model ID: PS-2019
- ▶ **50 μm XYZ Piezo Scanner for TT-2 AFM**
Model ID: PS-2010
- ▶ **15 μm XYZ Piezo Scanner for TT-2 AFM**
Model ID: PS-2011

The PS-2010, PS-2011, and PS-2019 **piezoelectric scanners** are designed for use with the AFMWorkshop TT-AFM, and scan samples in the X-Y- and Z-axis. All three scanners use temperature compensated strain gauges for linearizing scans in the X- and Y-axis. The PS-2010 and PS-2019 have a temperature compensated strain gauge in the Z axis, while the PS-2011 does not.

All three scanners use a modified tripod design for creating motion in the XY-axis. Motion is generated through a lever arm. Animations on the AFMWorkshop website (www.afmworkshop.com) illustrate how the scanners operate. Each scanner contains a PC board with circuits for measuring ceramic motion with the strain gauge as well as a 20 pin ribbon cable connector. The scanners are attached to the XY manual positioner with three M6 socket head screws.



PS-2010 scanner with standard sample holder. Two magnets secure AFM sample disks.



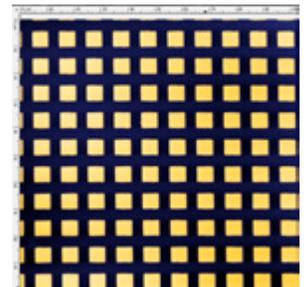
PS-2011 scanner with leveling sample puck.

▶ **Sample Holding Stage**

Mounted on standard AFM metal disks, samples are held on an aluminum metal plate with two magnets. As shipped, the sample holder is electronically grounded to the microscope stage to help eliminate unwanted effects from sample charging. Included with each scanner is a leveling sample puck. The puck enables samples to be leveled, reducing the AFM image background bow to less than a few nanometers. The leveling sample puck is magnetically held to the sample stage and has three set screws to level the puck relative to the XY scan axis.

▶ **Interchangeable**

All three scanners are interchangeable. The scanners are removed from the TT-AFM stage by simply unscrewing three M6 socket head screws and unplugging a 20 pin ribbon cable. It takes less than 5 minutes to remove one scanner and to replace it with another scanner.



Vibrating mode AFM image of a test pattern illustrating a 100 X 100 μm scan. The pitch in the XY-axis is 10 μm . Measured with the PS-2019 scanner.

Scanner Specifications

100 X 100 X 17

50 X 50 X 17

15 X 15 X 7

Engineering Specifications

» XY Resolution	0.010 nm	0.005 nm	0.003 nm
» XY Linearity	<0.1%	<0.1%	<0.1%
» Z Resolution	0.003 nm	0.003 nm	0.0015 nm
» Z Linearity	<0.1%	<0.1%	<0.1%

Performance Specifications

» XY Range	100 μ m	50 μ m	15 μ m
» XY Linearity	<1%	<1%	<1%
» XY Resolution			
• Closed Loop	<6 nm	<3 nm	<1 nm
• Open Loop	<1 nm	<1 nm	<0.3 nm
» Z Range	17 μ m	17 μ m	7 μ m
» Z Linearity			
• Open Loop	<5%	<5%	<5%
• Closed Loop	<1%	<1%	N.A.
» Z Sensor Noise	1 nm	1 nm	N.A.
» Z Feedback Noise	<0.15 nm	<0.15 nm	<0.08 nm

Actuator Type

Piezo

Piezo

Piezo

Design

Modified Tripod

Modified Tripod

Modified Tripod

XY Sensor Type

Strain Gauge

Strain Gauge

Strain Gauge

Z Sensor Type

Strain Gauge

Strain Gauge

N.A.